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AMENDMENTS TO THE CLAIMS

- (withdrawn): A method for manufacturing a light emitting diode having a transparent substrate, the method comprising:
- forming a semiconductor multilayer on a first substrate producing a first multilayer structure;
 - forming an amorphous interface layer on a second substrate, the second substrate being transparent in nature, producing a second multilayer structure;
 - bonding the first multilayer structure to the second multilayer structure, producing a third multilayer structure; and
 - removing the first substrate from the third multilayer structure.
 - (withdrawn): The method of claim 1 further comprising a step of forming a
 transparent conductive layer on the third multilayer structure after removing
 the first substrate.
 - 3. (withdrawn): The method of claim 1, wherein the amorphous interface layer is made of at least one selected from a group comprising indium tin oxide, indium cadmium oxide, indium tin oxide, and transparent conductive adhesive agent.
 - 4. (withdrawn): A method for manufacturing a light emitting diode, comprising:
 - forming a semiconductor multilayer on a first substrate producing a first multilayer structure;
 - forming an amorphous interface layer on a second substrate, the second substrate being transparent in nature, producing a second multilayer structure;
 - bonding the first multilayer structure to the second multilayer structure, producing a third multilayer structure; and
- removing the first substrate from the third multilayer structure.
 - 5. (withdrawn): The method of claim 4 further comprising a step of forming a

transparent conductive layer on the third multilayer structure after removing the first substrate.

- 6. (withdrawn): The method of claim 4, wherein the amorphous interface layer is made of at least one selected from a group comprising indium tin oxide, cadmium tin oxide, antimony tin oxide, and transparent conductive adhesive agent.
- 7. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
 - a transparent substrate;

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- an amorphous interface layer formed on the transparent substrate;
- a top surface of the amorphous interface layer comprising a first surface region and a second surface region;
- 15 a p⁺-type contact layer formed on the first surface region;
 - a p-type cladding layer formed on the p⁺-type contact layer;
 - a multiple quantum well (MQW) light-emitting layer formed on the p-type cladding layer;
 - an n-type cladding layer formed on the MQW light-emitting layer;
- 20 an n-type stop layer formed on the n-type cladding layer;
 - a transparent conductive layer formed on the n-type stop layer;
 - a first electrode formed on the transparent conductive layer; and
 - a second electrode formed on the second surface region.
- 8. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
 - a transparent substrate comprising sapphire;
 - an amorphous interface layer formed on the transparent substrate, a top surface of the amorphous interface layer comprising a first surface region and a second surface region;
 - a contact layer of p⁺-type GaAs formed on the first surface region;
 - a p-type cladding layer of p-type AlGaInP formed on the contact layer.

- a light-emitting layer of AlGaInP formed on the p-type cladding layer;
 an n-type cladding layer of n-type AlGaInP formed on the light-emitting layer;
 a stop layer of n-type AlGaAs formed on the n-type cladding layer;
 an ITO transparent conductive layer formed on the stop layer.

 5 a first electrode formed on the ITO transparent conductive layer.
 a second electrode formed on the second surface region.
 - 9. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
- an ohmic contact electrode;
 a p-type transparent substrate formed on the ohmic contact electrode;
 a first p*-type contact layer formed on the transparent substrate;
 an amorphous interface layer formed on the first p*-type contact layer;
 a second p*-type contact layer formed on the amorphous interface layer;
 a p-type cladding layer formed on the second p*-type contact layer;
 a light-emitting layer formed on the p-type cladding layer;
 an n-type cladding layer formed on the light-emitting layer;
 an n-type stop layer formed on the n-type cladding layer;
 a transparent conductive layer formed on the n-type stop layer; and
 a first electrode formed on the transparent conductive layer.
 - 10. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:

an ohmic contact electrode;

- a p-type GaP transparent substrate formed on the ohmic contact electrode;
 - a first p⁺-type contact layer of p⁺-type GaAs formed on the p-type GaP transparent substrate;
 - an indium tin oxide amorphous interface layer formed on the first p⁺-type contact layer;
- a second p⁺-type contact layer of p⁺-type GaAs formed on the indium tin oxide amorphous interface layer;
 - a p-type cladding layer of a p-type AlGaInP formed on the second p+type

contact layer;

- a multiple quantum well light-emitting layer of AlGaInP formed on the p-type cladding layer;
- an n-type cladding layer of n-type AlGaInP formed on the light-emitting layer;
- 5 a stop layer of n-type AlGaAs formed on the n-type cladding layer;
 - an ITO transparent conductive layer formed on the stop layer;
 - a first electrode formed on the ITO transparent conductive layer.
 - (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
 - a first electrode;

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- an n-type transparent substrate formed on the first electrode;
- an amorphous interface layer formed on the n-type transparent substrate;
- an n-type contact layer formed on the amorphous interface layer;
- an n-type cladding layer formed on the n-type contact layer;
 - a light-emitting layer formed on the n-type cladding layer;
 - a p-type cladding layer formed on the light-emitting layer;
 - a p-type buffer layer formed on the p-type cladding layer;
 - a p⁺-type contact layer formed on the p-type buffer layer;
- a transparent conductive layer formed on the p⁺-type contact layer; and
 - a second electrode formed on the transparent conductive layer.
 - 12. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
- 25 a first electrode;
 - a transparent substrate of n-type GaP formed on the first electrode;
 - an indium tin oxide (ITO) amorphous interface layer formed on the transparent substrate of n-type GaP;
 - a contact layer of n-type GaP formed on the ITO amorphous interface layer;
- 30 a cladding layer of n-type AlGaInP formed on the contact layer of n-type GaP;
 - a multiple quantum well (MQW) light-emitting layer of AlGaInP formed on the cladding layer of n-type AlGaInP;

- a cladding layer of p-type AlGaInP formed on the MQW light-emitting layer of AlGaInP;
- a buffer layer of p-type AlGaAs formed on the cladding layer of p-type AlGaInP;
- a contact layer of p⁺-type GaAs formed on the buffer layer of p-type AlGaAs;
- an ITO transparent conductive layer formed on the contact layer of p⁺-type GaAs; and
 - a second electrode formed on the ITO transparent conductive layer.
 - 13. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
 - a transparent substrate;

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- an amorphous interface layer formed on the transparent substrate, a top surface of the amorphous interface layer comprising a first surface region and a second surface region;
- an n⁺-type reverse-tunneling contact layer formed on the first surface region;
 - a p-type cladding layer of formed on the n+-type reverse-tunneling contact layer;
 - a light-emitting layer formed on the p-type cladding layer;
 - an n-type cladding layer formed on the light-emitting layer;
 - a first contact electrode formed on the n-type cladding layer; and
- a second electrode formed on the second surface region.
 - 14. (original): A light emitting diode having a transparent substrate, the light emitting diode comprising:
 - a transparent substrate comprising glass;
- an indium tin oxide (ITO) amorphous interface layer formed on the transparent substrate, a top surface of the ITO amorphous interface layer comprising a first surface region and a second surface region;
 - a reverse-tunneling contact layer of n⁺-type InGaN formed on the first surface region;
- a cladding layer of a p-type GaN formed on the reverse-tunneling contact layer of n⁺-type InGaN;
 - a multiple quantum well (MQW) light-emitting layer of InGaN formed on the

cladding layer of a p-type GaN;

- a cladding layer of n-type GaN formed on the MQW light-emitting layer of InGaN;
- a first contact electrode formed on the cladding layer of n-type GaN;
- 5 a second electrode formed on the second surface region.